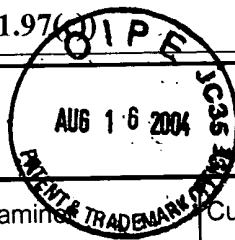


TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT
(Under 37 CFR 1.97(b) or 1.97(c))

1#W
Docket No.
FIS920040187US1

In Re Application Of: David V. Horak et al.



Application No.

Filing Date

Examiner

Customer No.

Group Art Unit

Confirmation No.

101710, 447

7-12-04

Title:

FEATURE DIMENSION DEVIATION CORRECTION SYSTEM, METHOD AND PROGRAM PRODUCT

Address to:

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

37 CFR 1.97(b)

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

37 CFR 1.97(c)

2. ☐ The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), provided that the Information Disclosure Statement is filed before the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by one of:

☐ the statement specified in 37 CFR 1.97(e);

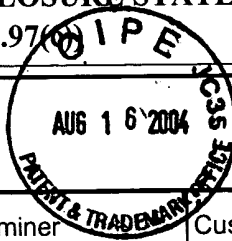
OR

☐ the fee set forth in 37 CFR 1.17(p).

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT
(Under 37 CFR 1.97(b) or 1.97(f))

Docket No.
FIS920040187US1

In Re Application: David V. Horak et al.



Application No. 10/710,447	Filing Date 7-12-04	Examiner	Customer No.	Group Art Unit	Confirmation No.
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FEATURE DIMENSION DEVIATION CORRECTION SYSTEM, METHOD AND PROGRAM PRODUCT

Payment of Fee

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of _____ is attached.
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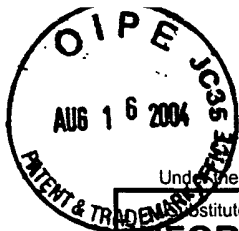
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Complete if Known	
		Application Number	10/710,447
		Filing Date	7-12-04
		First Named Inventor	David V. Horak et al.
		Group Art Unit	
		Examiner Name	
Sheet 1 of 1	Attorney Docket Number	FIS920040187US1	

OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		BAUM, C.C. et al., "Scatterometry for Post-Etch Polysilicon Gate Metrology," Proceedings of the SPIE - The International Society for Optical Engineering Conference, Vol. 3677, Pt. 1-2, pp. 148-158.	
		AL-ASSAAD, R.M. et al., "Profile Parameter Accuracy Determined from Scatterometric Measurements," Proceedings of the SPIE - The International Society for Optical Engineering Conference, Vol. 4692, pp. 17-28.	
		DREGE, EMMANUEL M. et al., "Linearized Inversion of Scatterometric Data to Obtain Surface Profile Information," Optical Engineering, Vol. 41, No. 1, pp. 225-236.	

Examiner Signature		Date Considered	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

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